

Title (en)  
ELECTRON MICROSCOPE, AND METHOD FOR OBSERVING MEASUREMENT SAMPLE

Title (de)  
ELEKTRONENMIKROSKOP UND VERFAHREN ZUR BEOBACHTUNG EINER MESSPROBE

Title (fr)  
MICROSCOPE ÉLECTRONIQUE ET PROCÉDÉ D'OBSERVATION D'ÉCHANTILLON DE MESURE

Publication  
**EP 3757558 A4 20211117 (EN)**

Application  
**EP 19757961 A 20190218**

Priority  
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Abstract (en)  
[origin: EP3757558A1] Provided are an electron microscope and a method for observing a measurement sample, which enable non-destructive observation. An electron microscope (1) includes: a laser light source (2) for generating a CW laser (7); an irradiation lens system (focusing lens (4) and objective lens (6)) for irradiating a measurement sample (30) with the CW laser (7); an energy analyzer (22) for dispersing, depending on energy, photoelectrons emitted from the measurement sample (30) by the CW laser (7); an energy slit (23) for allowing a photoelectron with a specified energy to pass; an electron beam detector (25) for detecting the photoelectron passed through the energy slit (23); a first electron lens system (21) for focusing the photoelectrons emitted from the measurement sample (30) onto the energy analyzer (22); and a second electron lens system (24) for projecting the photoelectron passed through the energy slit (23) onto the electron beam detector (25).

IPC 8 full level  
**G01N 23/227** (2018.01); **G02B 21/00** (2006.01); **H01J 37/285** (2006.01); **G01R 31/265** (2006.01)

CPC (source: EP KR US)  
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Citation (search report)  
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• See also references of WO 2019163715A1

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